

POLYELECTROLYTE

MULTILAYERS

PREPARATION,

CHARACTERIZATION,

INTERNAL STRUCTURE.

## Main Items:

- What are polyelectrolytes?

- .Definition

- .Examples

- Formation of polyelectrolyte multilayers.

- .Adsorption mechanism

- .Thin Layers preparation

- Characterization Techniques.

- .Ellipsometry

- .X-ray Reflectivity

- Factors affecting formation of multilayers.

- .Polyelectrolyte Concentration.

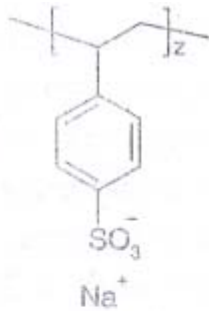
- .Ionic Strength.

- .Charge Density.

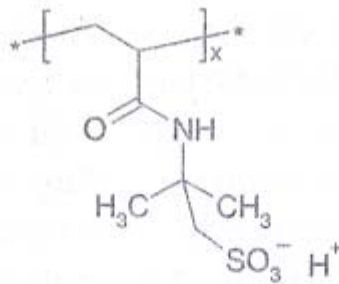
## Polyelectrolytes :

*Macromolecules “ Polymer Chains “ having charges distributed along the chain, these charges can be positive “Polycations“ or negative “Polyanions“ beside the oppositely charged “Counter Ion“.*

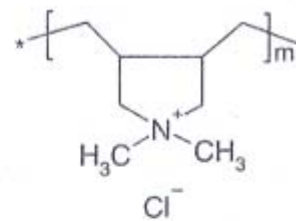
Examples:



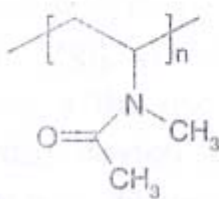
PSS



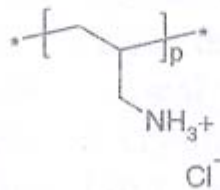
PAMPS



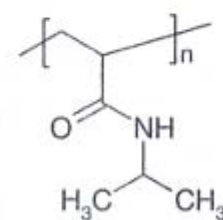
PDADMAC



PNMVA



PAH

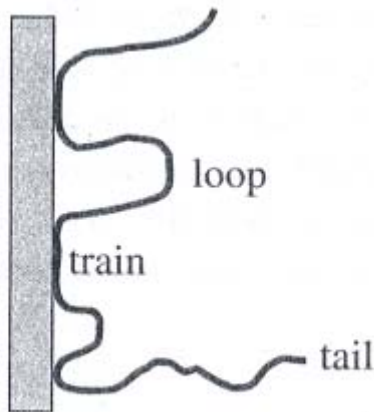


PNIPAM

## CONCEPT:

Adsorption of one layer on the substrate, then the upcoming layers can adsorb layer by layer on each other; THE DRIVING FORCE is the ELECTROSTATIC ATTRACTION between oppositely charged chains.

## ADSORPTION MECHANISM:



Transport of the polymer molecule to the interface.

The primary adsorption Step.

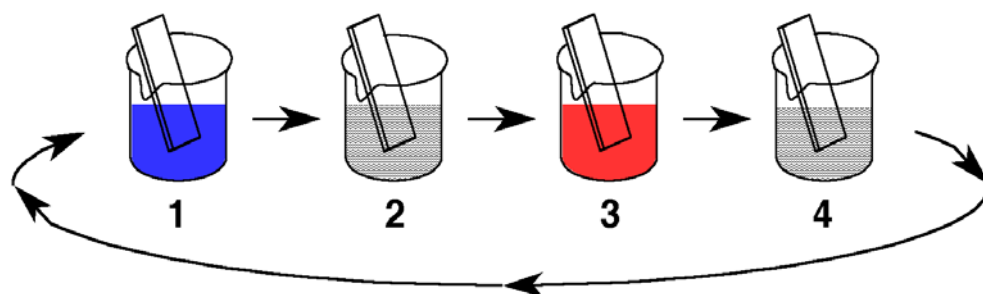
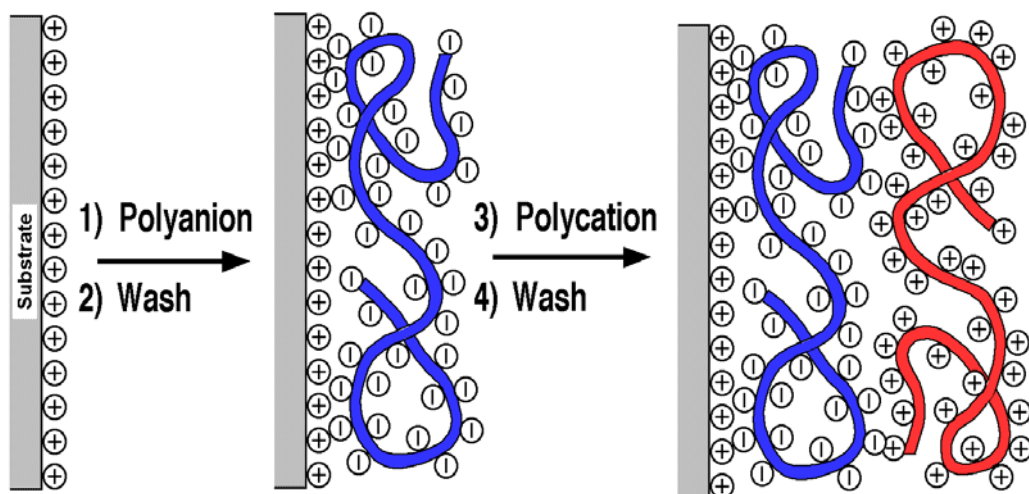
Arrangement of the adsorbed molecule.

conformations were predicted by theoretical model

molecules transport is governed by Diffusion Coefficient ranging from  $10^{-9}$  to  $10^{-7}$   $\text{Cm}^2/\text{s}$

## Preparation:

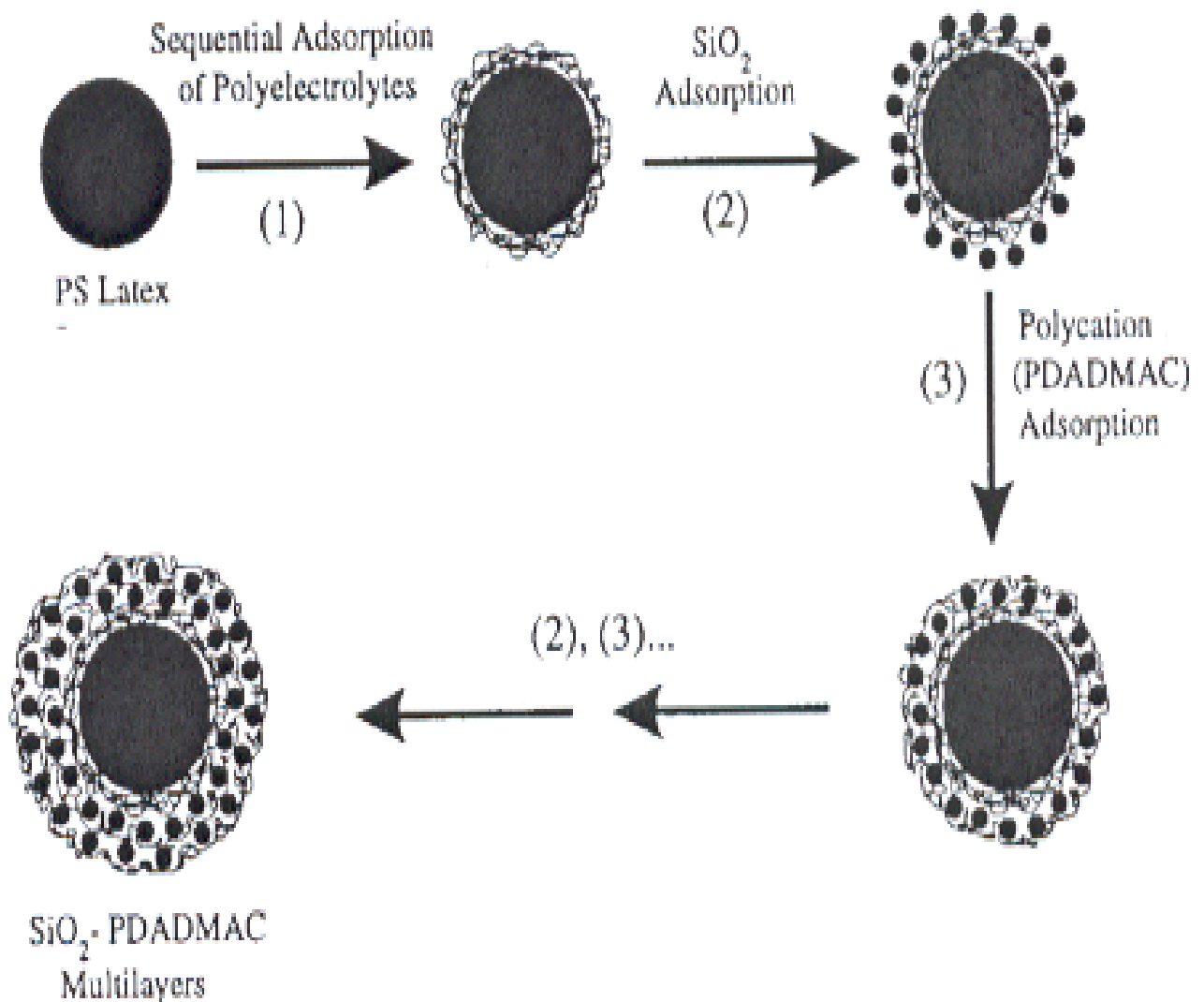
- First ; Cleaning the Silicon Substrates in Acidic Solution “ e.g. Pirana Solution  $\text{H}_2\text{SO}_4$ :  $\text{H}_2\text{O}_2$  in ratio 1:1” then rinsed by distilled water. This Cleaning is to get rid of wax and to afford a hydrophilic surface for the the polymer chains.
- Preparation of NaCl solution of certain molarity, in which the polymer is dissolved at certain concentration.
- Then dipping the substrate for a certain time in the polyanion/polycation solution, “ ideally 20 min .” followed by washing steps then the other oppositely charged polymer and again the washing steps and so on.



## Multilayers on POLYMER LATEX:

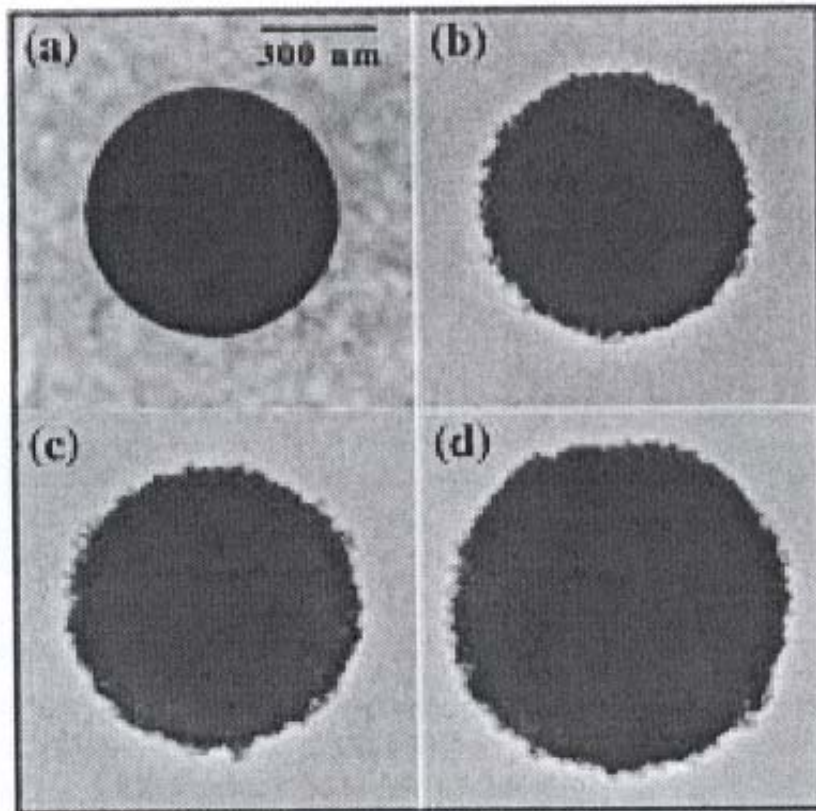
### *Assembly of multilayers on PS Latex .*

- 1- Adsorption of oppositely charged polyelectrolytes (PDADMAC/ PSS/PDADMAC) or ( $\text{Pr}_3$ ) in order to produce a smooth and uniformly positively charged outer surface to facilitate the adsorption of the negatively charged  $\text{SiO}_2$ .
- 2- Adsorption of  $\text{SiO}_2$
- 3- Adsorption of PDADMAC.



## Latex growth characterization:

SFM Images:



a- Uncoated PS Latex

And PS Latices coated with  $[Pr_3/(SiO_2/PDADMAC)_N]$  ;

b-  $N = 1$

c-  $N = 2$

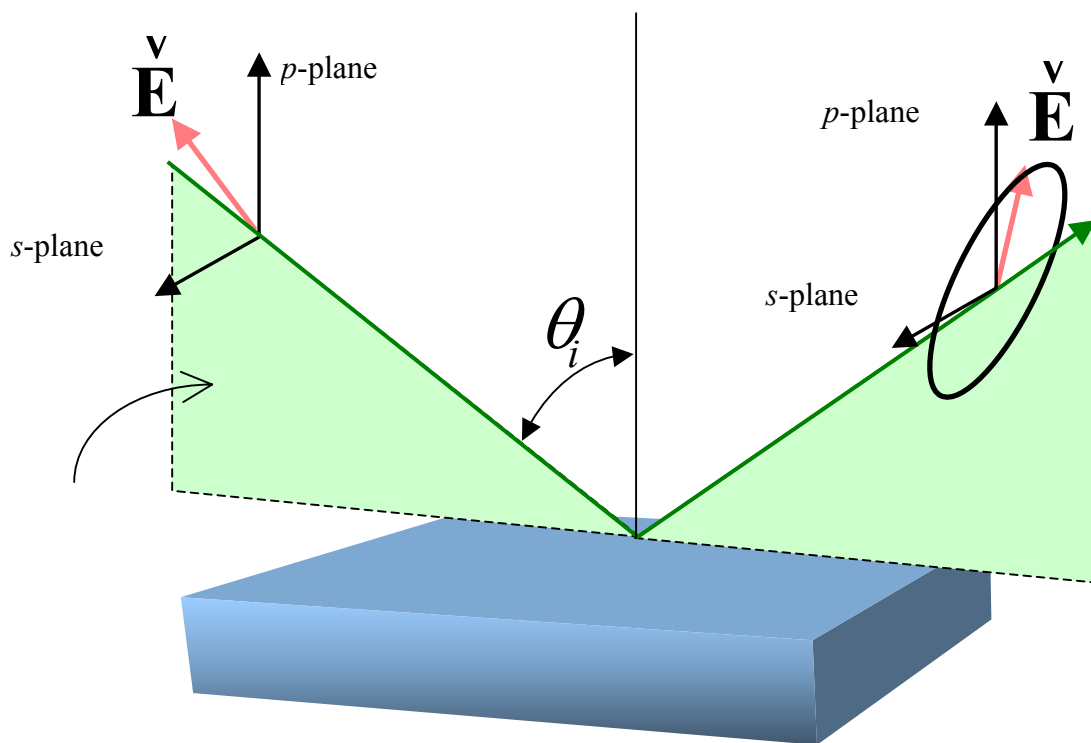
d-  $N = 4$

- Increased Surface roughness due to  $SiO_2$  adsorption.
- regular growth of the  $SiO_2$  – PDADMAC multilayers is seen.

## Characterization Techniques:

- **Ellipsometry:** measures the change of polarization occurs for a monochromatic beam upon reflection at an interface between two media of two different refractive indices.

Giving accurate values for the film thickness  $d$  and refractive index  $n$



-The measurable quantities in Ellipsometry are

$\Delta$  the phase shift introduced by the film,

$\psi$  is amplitude of the reflected wave.

Related to the ellipticity  $\rho$  by:  $\rho = p/s = \tan\psi \exp(i\Delta)$  (1)

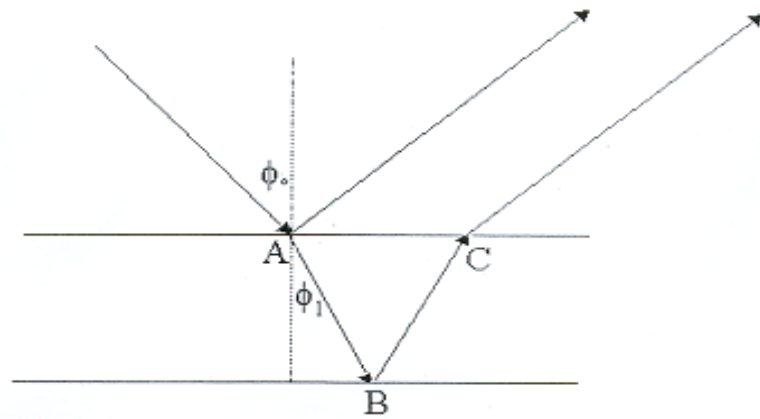
S and p are the Fresnel reflection coefficient for S and P polarized light respectively.



air

Adsorbed film

substrate



$$\sigma_0 = \left( \frac{2\pi}{\lambda_0} \right) n_1^* d_1 \cos \phi_1$$

Where :

$\sigma_0$  is the phase lag between A and C

$\lambda_0$  is the wavelength of the incident beam

$n_1^*$  is the refractive index of the film

$d_1$  is the film thickness

$\phi_1$  is the refraction angle at the first interface.

$$\tan \psi e^{i\Delta} = \left( \frac{p_1 + p_2 e^{-i2\sigma_0}}{1 + p_1 p_2 e^{-i2\sigma_0}} \right) \left( \frac{1 + s_1 s_2 e^{-i2\sigma_0}}{s_1 + s_2 e^{-i2\sigma_0}} \right)$$

## X- ray and Neutron Reflectivity:

# Properties:

| Property          | X-ray  | Neutrons                                       |
|-------------------|--|--|
| • Rest mass       | 0  | $1.675 * 10^{-27}$ kg                          |
| • Charge          | 0  | 0  |
| • Spin            | 1  | $\frac{1}{2}$                                  |
| • Energy          | $E = hc/\lambda \sim 10^4$ eV                        | $E = p^2/2m \sim 25$ meV                       |
| • Wavelength      | $1 \text{ \AA}$ for Cu $k_\alpha = 1.54 \text{ \AA}$ | $\sim 2 \text{ \AA}$                           |
| • Scattering type | elastic due to high energy                           | elastic and can be inelastic due to low energy |

## Refractive index:

$$n = 1 - \sigma - i \beta$$

for X-ray :  $\sigma = \lambda^2 / 2\pi \cdot \rho_s \cdot r_0$

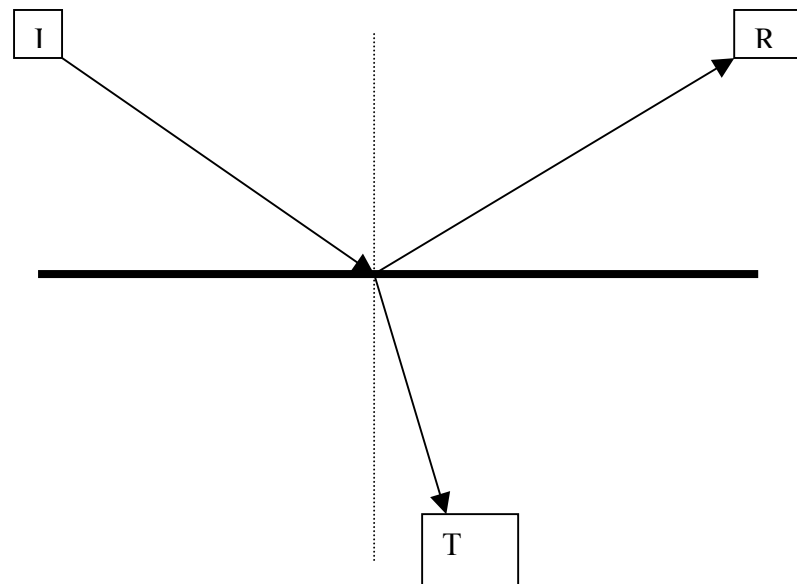
$\rho_s$  : electron density in the film [ $\text{\AA}^{-3}$ ]

$r_0$  : Thomson Radius ,  $2.82 \cdot 10^{-5}$  [ $\text{\AA}$ ]

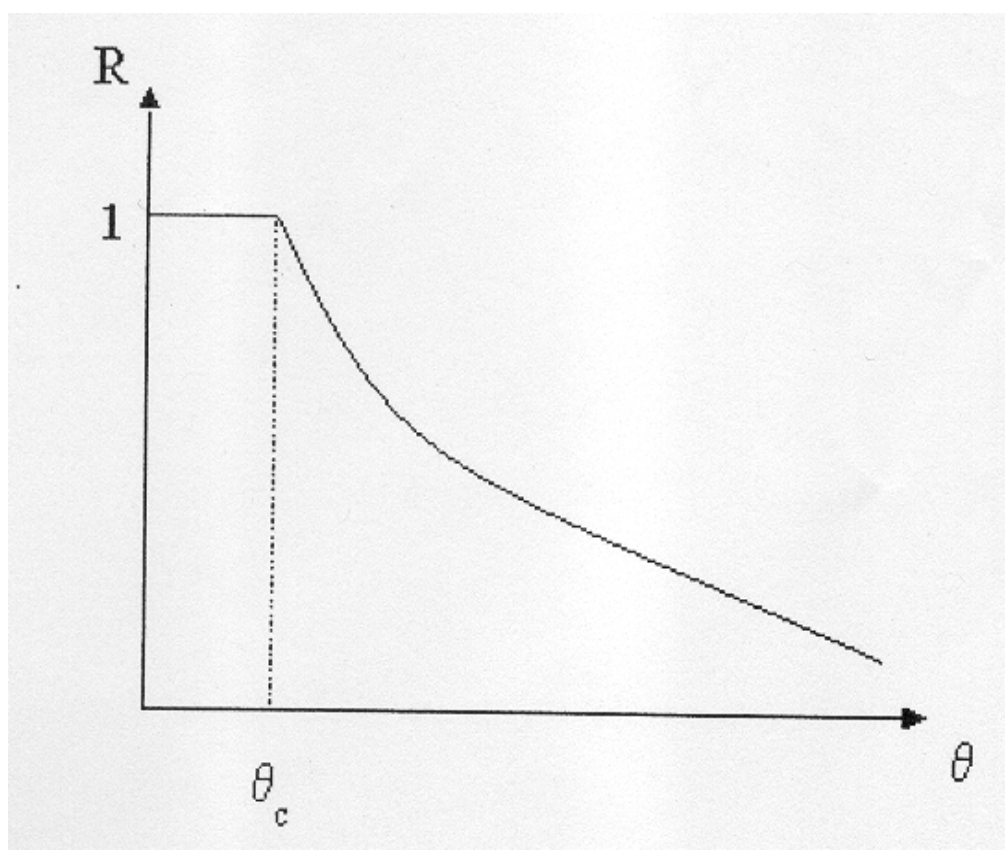
for Neutrons:  $\sigma = \lambda^2 / 2\pi \cdot N \cdot B$

$N$  : number density “number of nuclei in unit volume“ [ $\text{\AA}^{-3}$ ].  
 $B$  : scattering length of neutrons [ $\text{\AA}^\circ$ ].

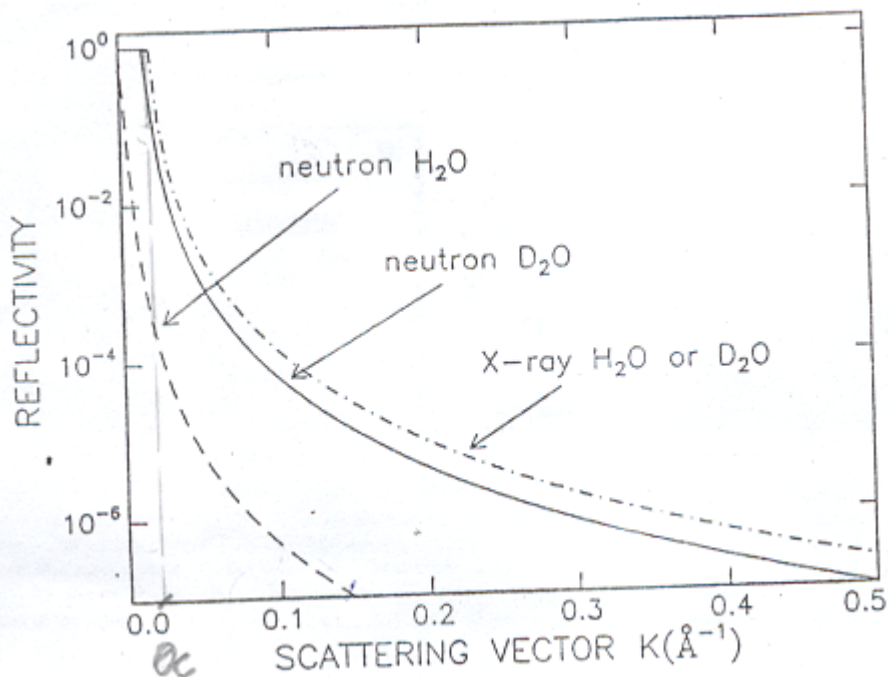
Reflection by Electrons and neutrons at surfaces:



A part from the incident beam is reflected and another part is transmitted, at small incidence angles everything is reflected until the critical angle  $\theta_c$ , after which the transmission starts and reflection decays exponentially.

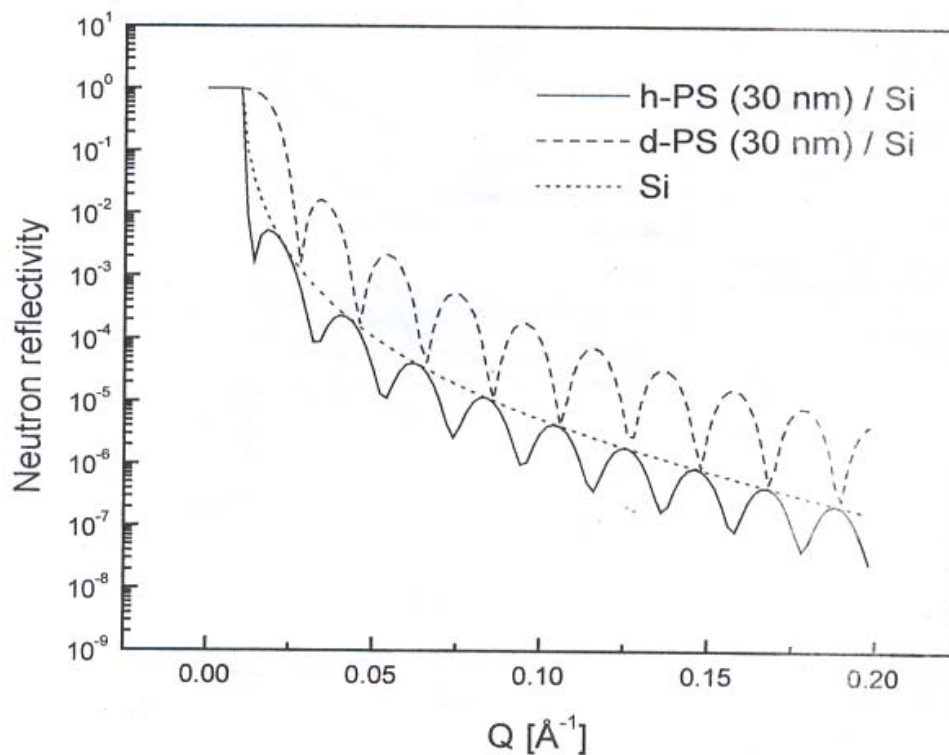


Reflectivity of Electrons and neutrons:

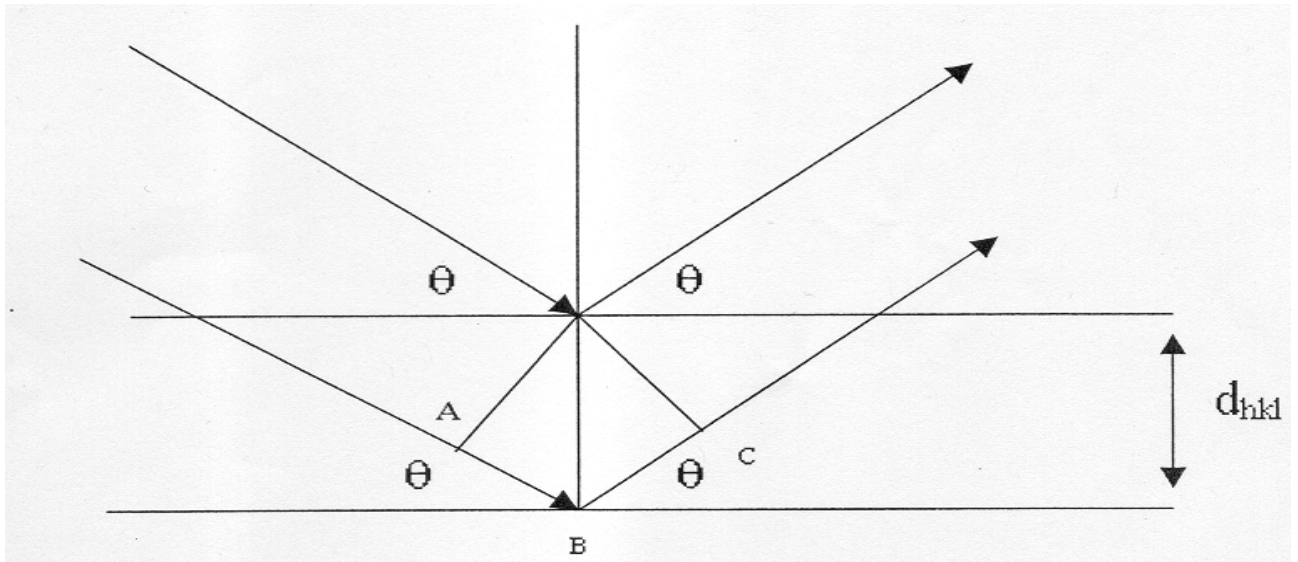


There is only  
difference between  
isotopes in case of  
neurons due to the  
different scattering

length values, but in case of x-ray both isotopes have the same electron density.



**Bragg Law:**

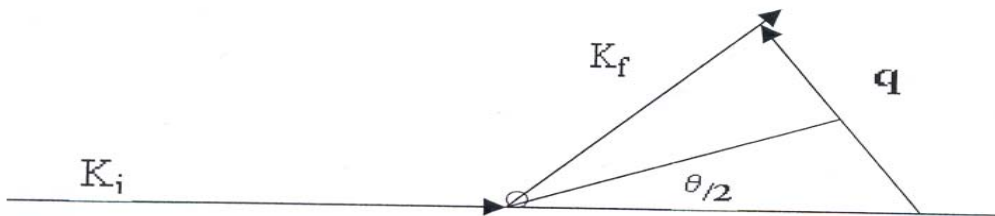


$$AB = d \sin \theta , \quad BC = d \sin \theta$$

$$AB + BC = 2 d \sin \theta$$

Path length difference must equal multiple the wavelength for constructive interference

$$2 d \sin \theta = n\lambda \quad , \quad n = 1, 2, \dots$$



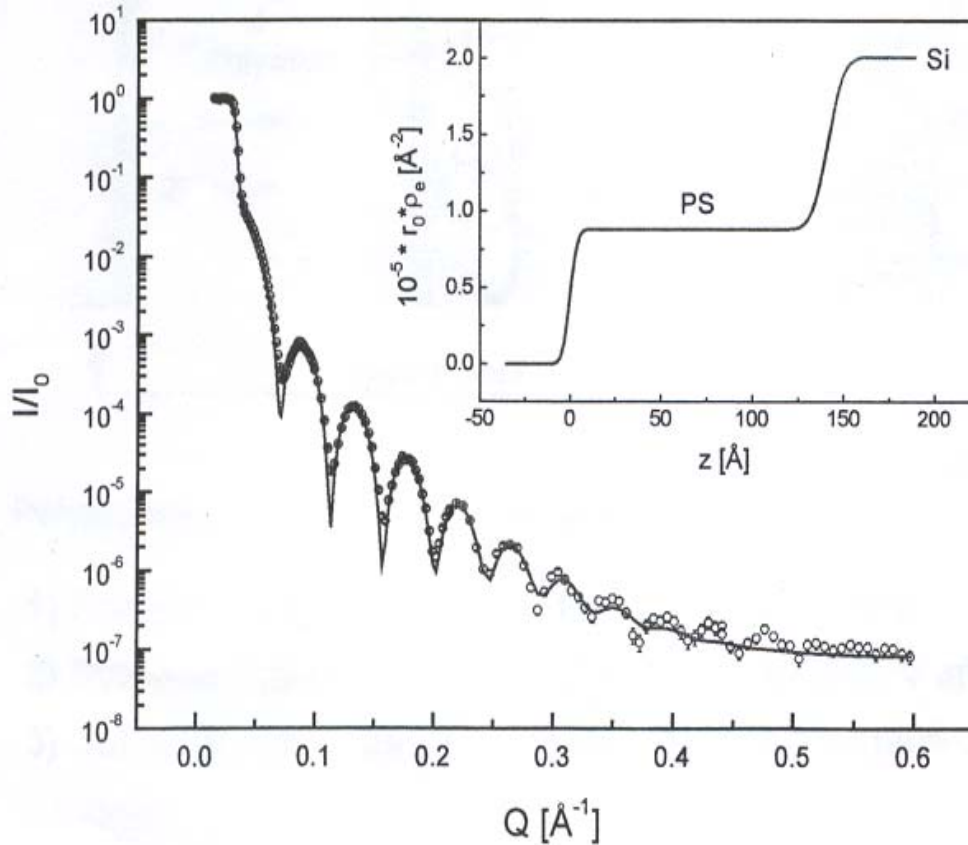
$q$  “scattering vector“ or “ momentum transfer“

$$q = 2 k \sin \theta/2 \quad , \quad k = 2\pi/\lambda$$

$$q = 4\pi/\lambda \cdot \sin\theta/2$$

$$q = 2\pi / d$$

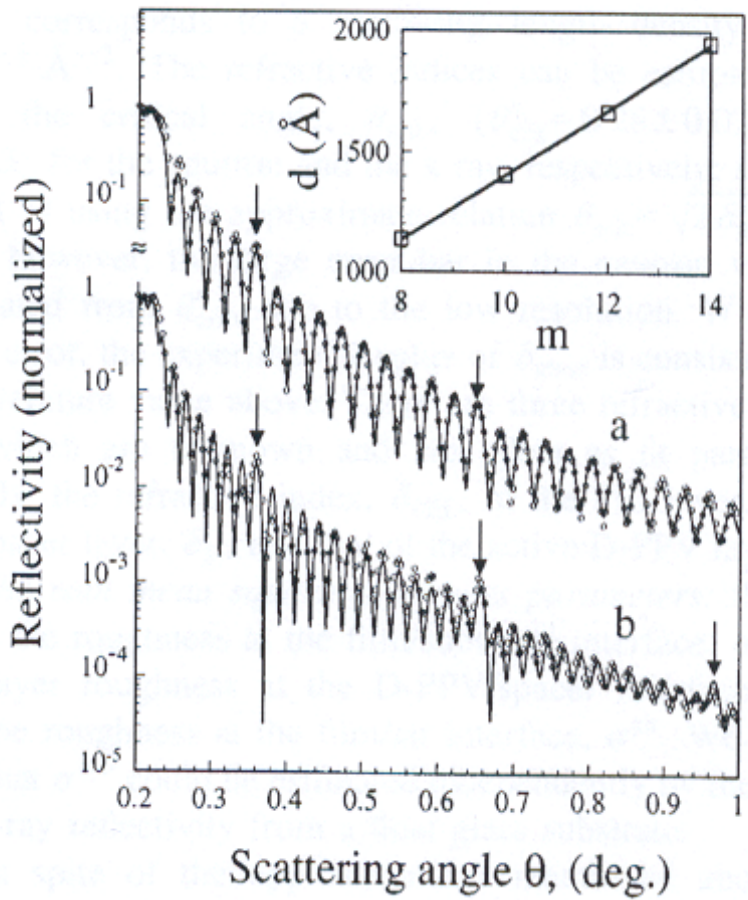
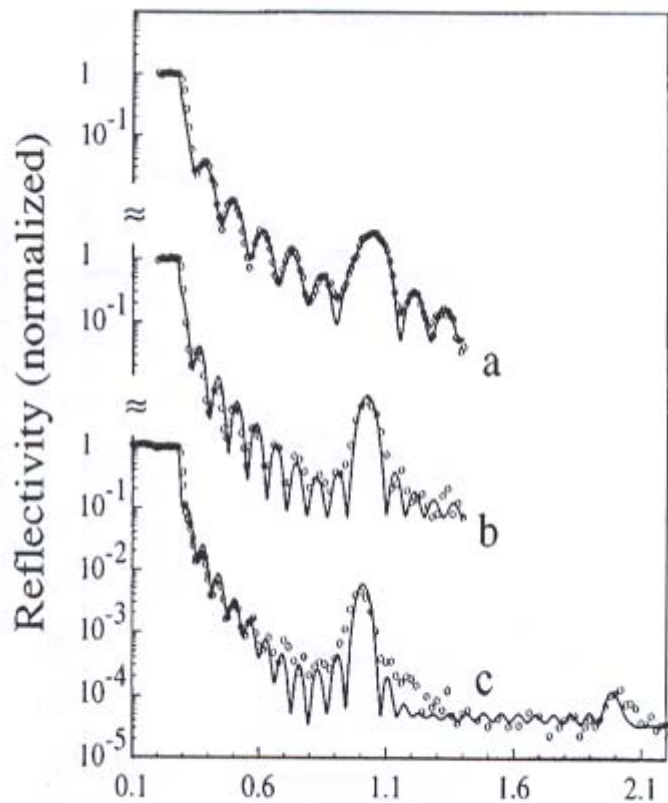
Information from Reflectivity curve:



the peaks are the points of constructive interference.

The distance between every two peaks is  $\Delta q$ , giving the value of  $d$  "lattice constant" or in case of thin films, gives the film thickness.

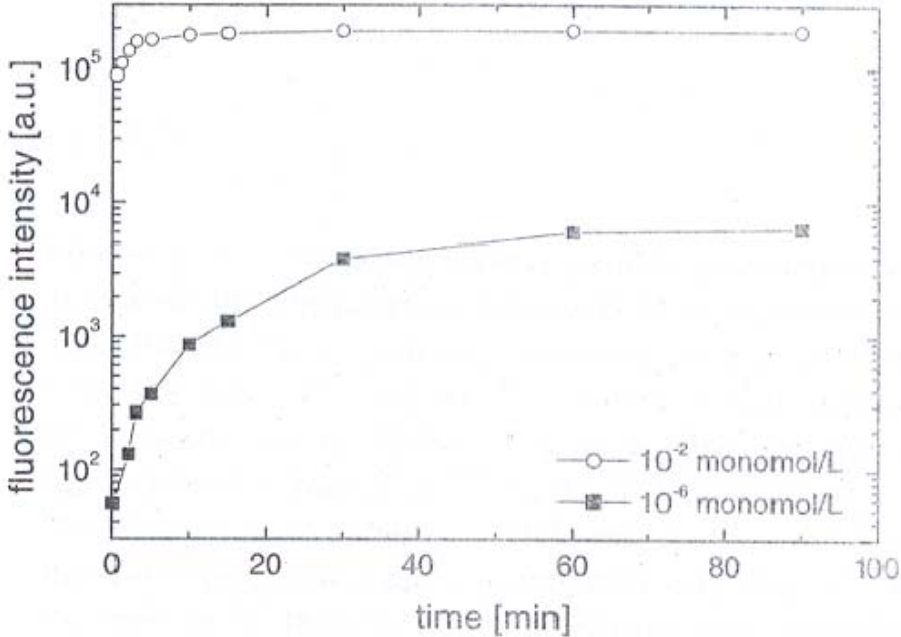
Legend is the Refractive index profile



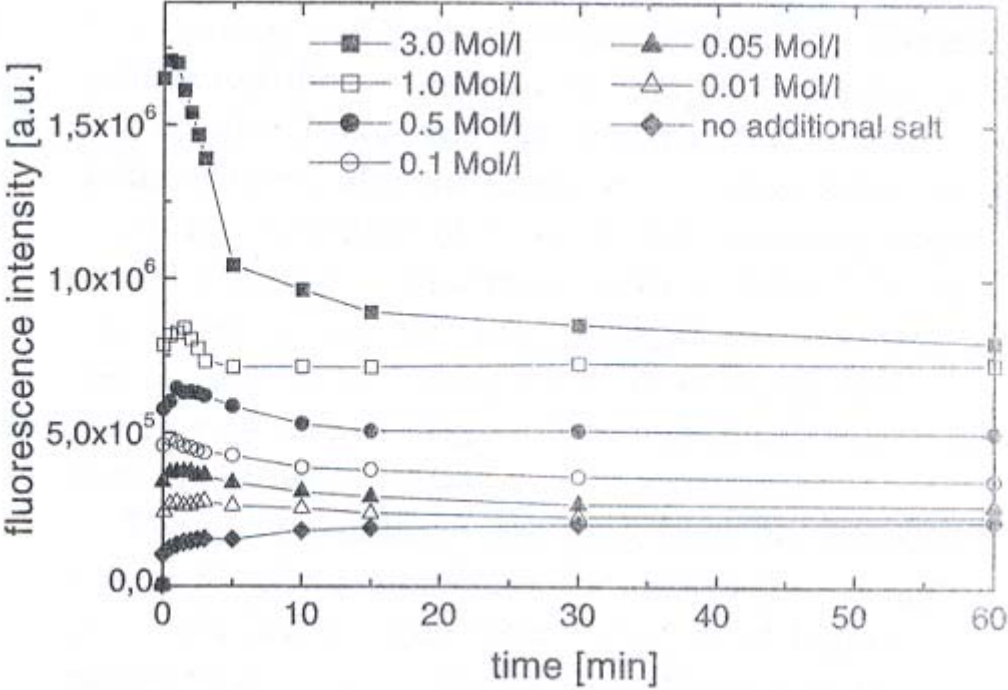


Multilayers Internal structure:

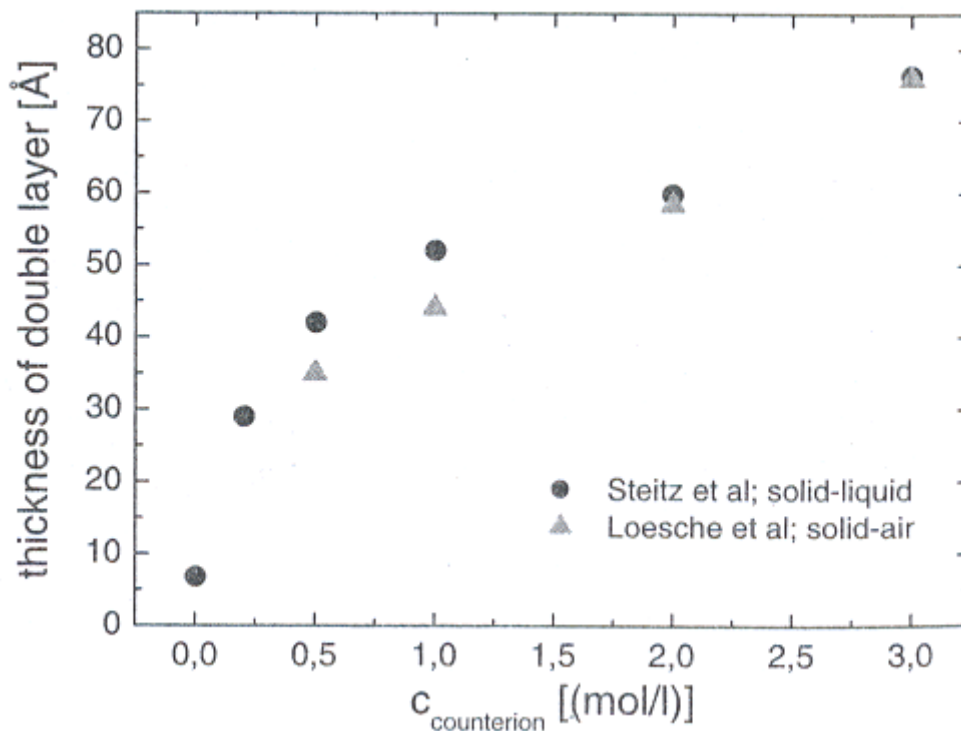
- POLYELECTROLYTE CONCENTRATION:



-Influence of IONIC STRENGTH:



## Factors affecting FILM THICKNESS:

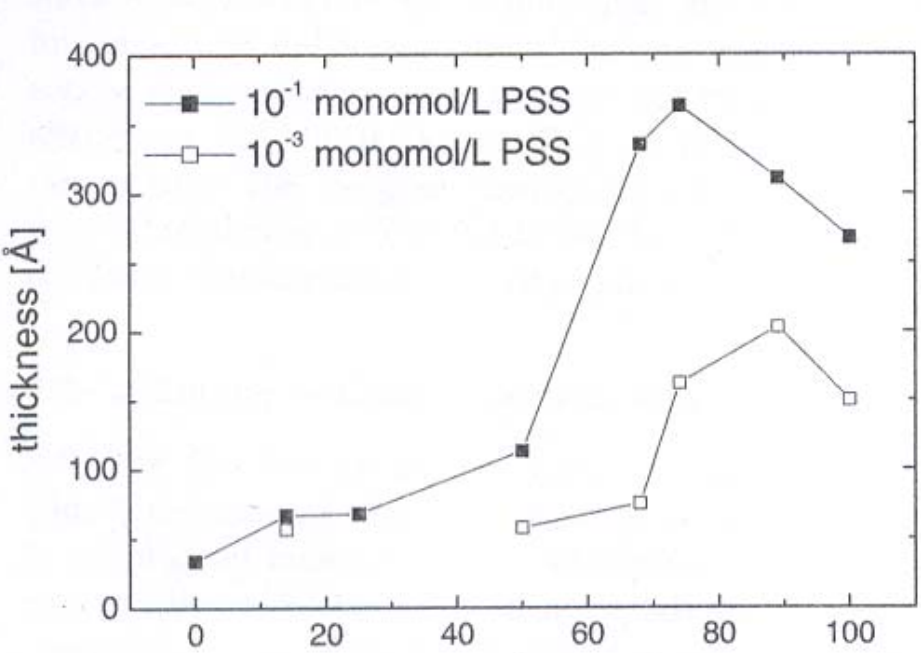


-HIGHER POLYELECTROLYTE CONCENTRATIONS GIVES HIGHER FLUORESCENCE INTENSITY.

- HIGHER SALT CONCENTRATIONS ALSO GIVES HIGH FLUORESCENCE INTENSITIES; *AT LOW IONIC STRENGTH THE CHARGES ALONG A CHAIN REPEL EACH OTHER YIELDING MORE STRECHED CHAINS “ HIGHER RADIUS OF GYRATION“ . AT HIGH IONIC STRENGTH THE CHARGES ALONG THE CHAIN ARE SCREENED YIELDING MORE COILED CHAINS “ DECREASE IN RADIUS OF GYRATION“ AND MORE FLEXIBLE CHAINS“DECREASE IN PERSISTANCE LENGTH“.*

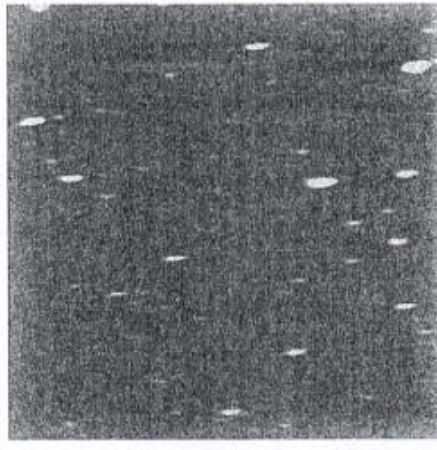
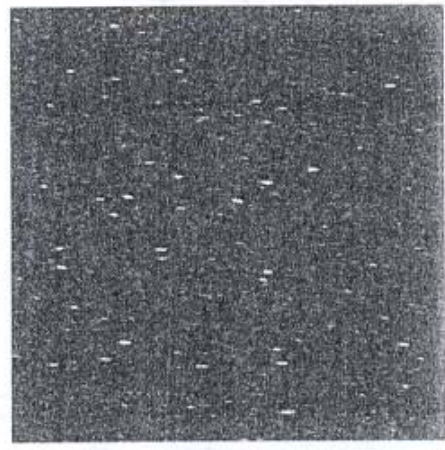
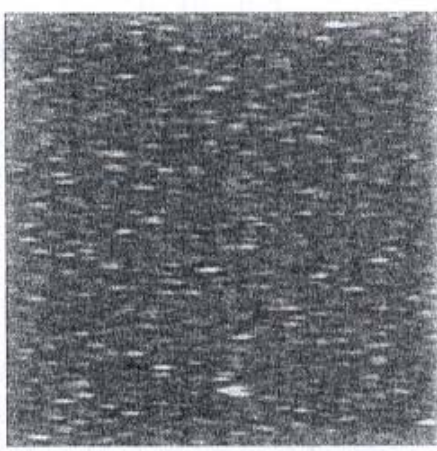
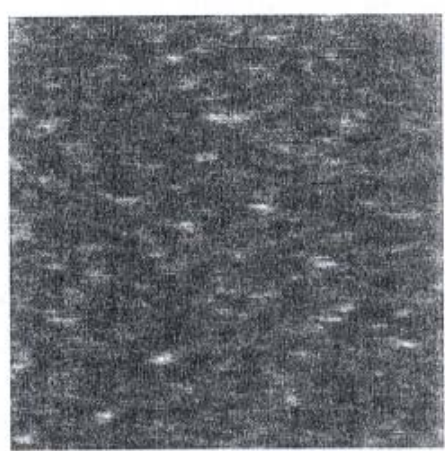
- THICKNESS INCREASES BY INCREASING THE SALT CONCENTRATION AS THE POLYMER CHAINS ARE MORE ENTANGLED.

# Charge Density



a

b



c

d

## REFERENCES:

- Handbook of polyelectrolyte and their applications ,chapter 14 “ internal structure of multilayers“ by Regine v. klitzing and Roland steitz.
- Langmuir, Vol. 17, No.15, 2001
- J. Appl. Physi., vol.83, No. 2, 15 january 1998
- SCIENCE. VOL. 277 . 29 August 1997
- Lectures by Roland Steitz at Physical chemistry Dept. TU Berlin.







